

Appl. No. 10/077,072
Amdt. dated 08/19/2003
Reply to Office action of 06/19/2003



PATENT

#12/C
9600
9503

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:)
FISCHER et al.) Group Art Unit: 2821
Application No: 10/077,072) Examiner: LEE, Wilson
Filed: February 14, 2002) Atty. Docket No: P0877
For: A PLASMA PROCESSING APPARATUS) Date: August 19, 2003
AND METHOD FOR CONFINING AN RF)
PLASMA UNDER VERY HIGH GAS FLOW)
AND RF POWER DENSITY CONDITIONS)

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on August 19, 2003

Signed: Sharon Tillery
Sharon Tillery

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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PRELIMINARY AMENDMENT

Dear Sir:

In response to the Final Office Action mailed on June 19, 2003, please enter the following amendments and remarks in the above-identified patent application:

Amendments to the specifications begin on page 2.

Amendments to the claims are reflected in the listing of claims, which begins on page 3 of this paper.

Remarks/Arguments begin on page 8 of this paper.